



Fig. 1

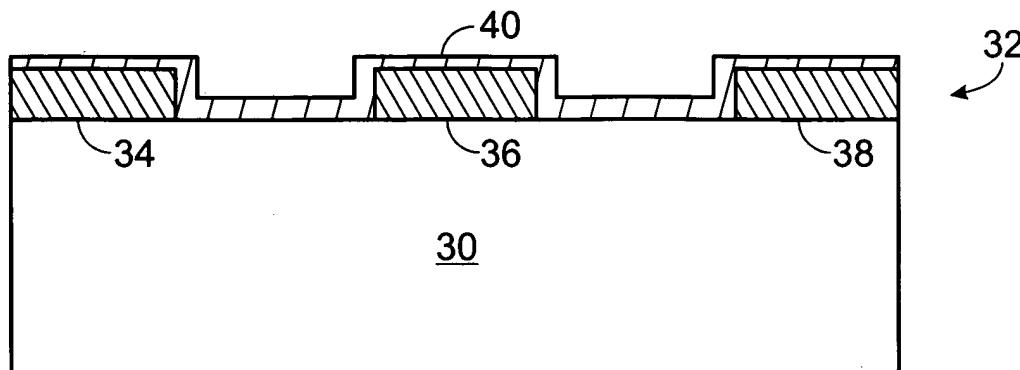


Fig. 2

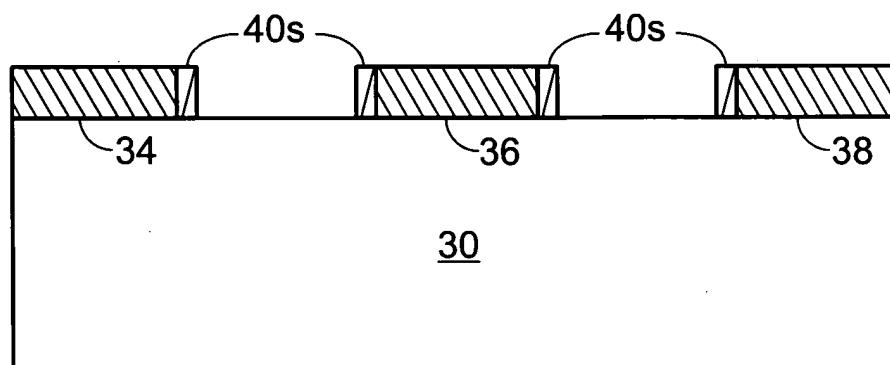


Fig. 3

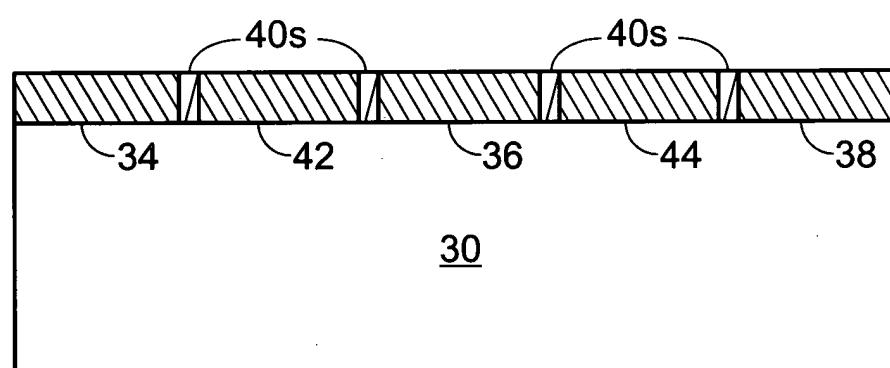
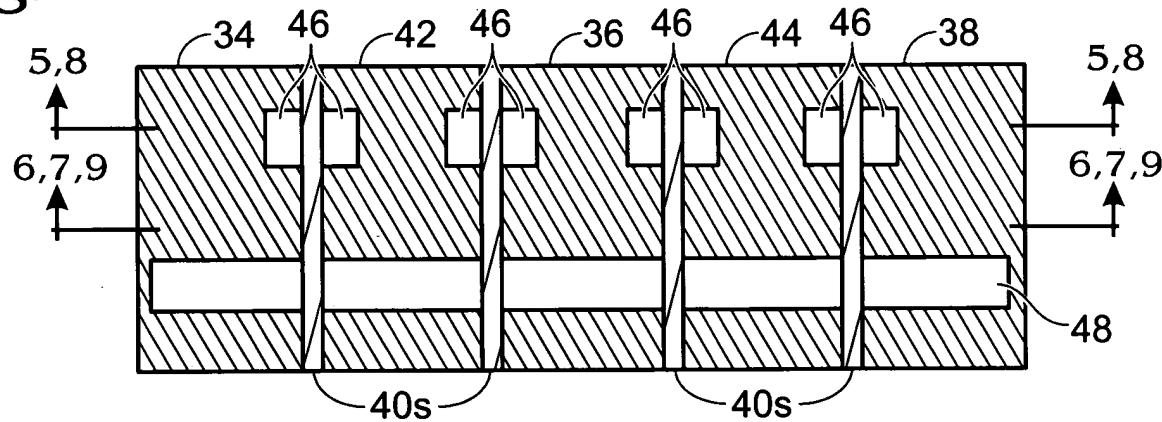


Fig. 4





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Fig. 5

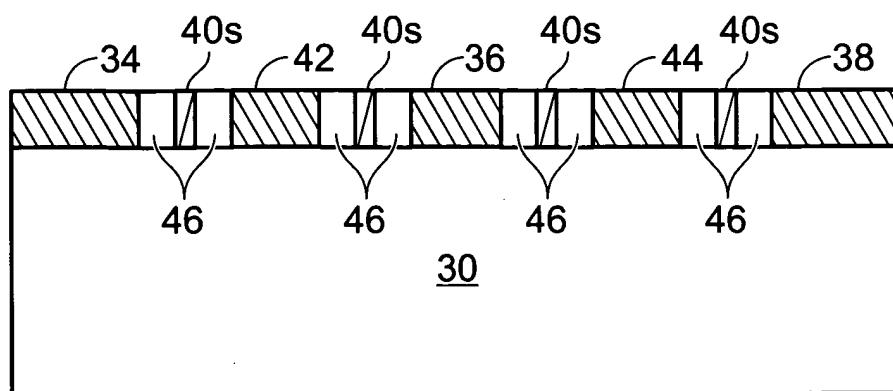


Fig. 6

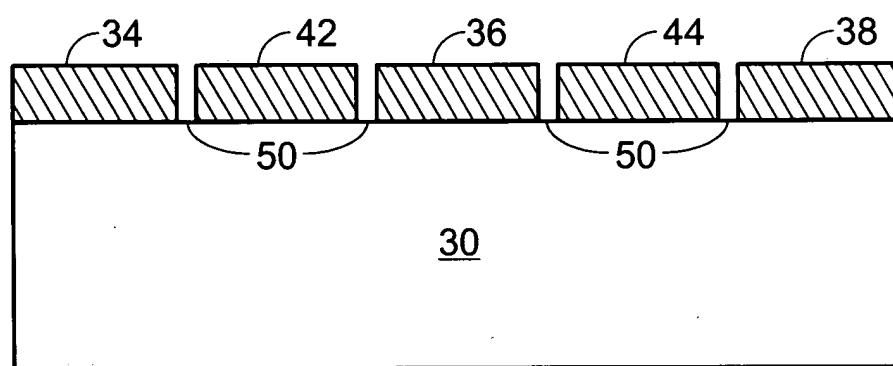


Fig. 7

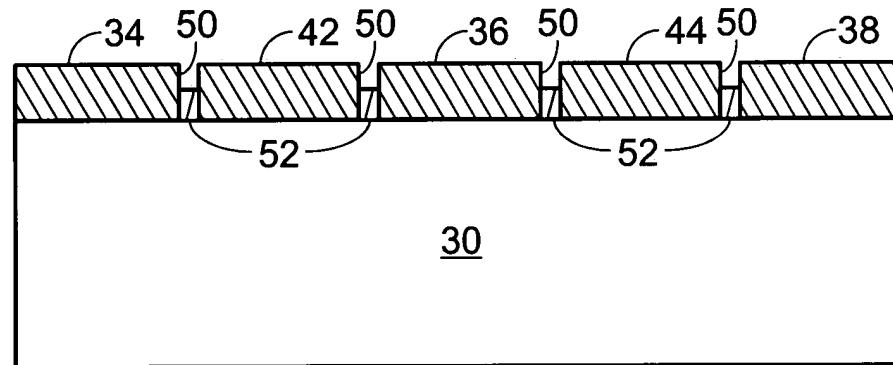


Fig. 8

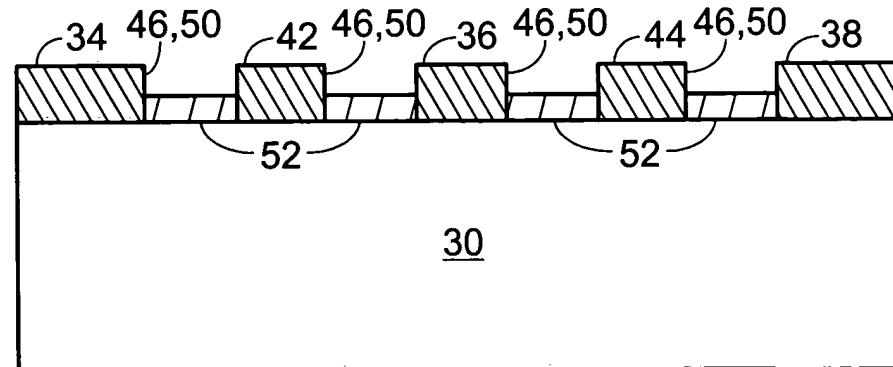




Fig. 9

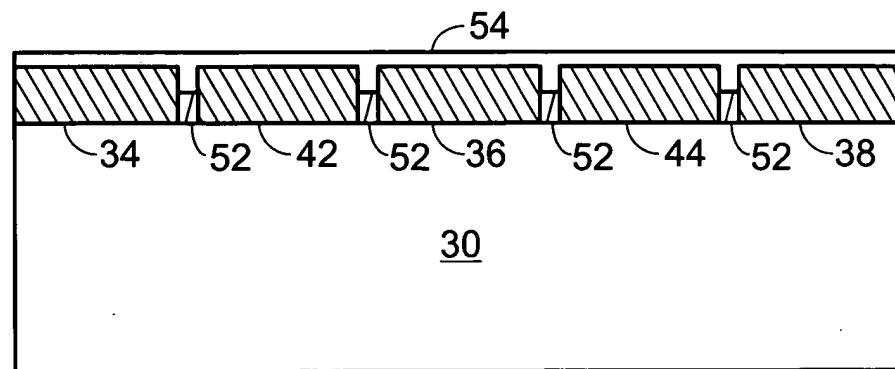


Fig. 10

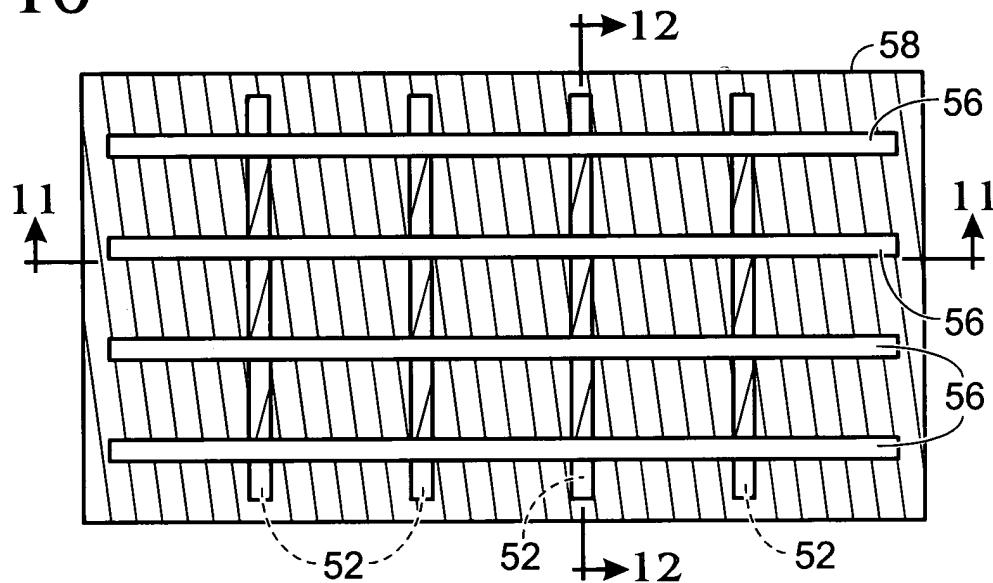


Fig. 11

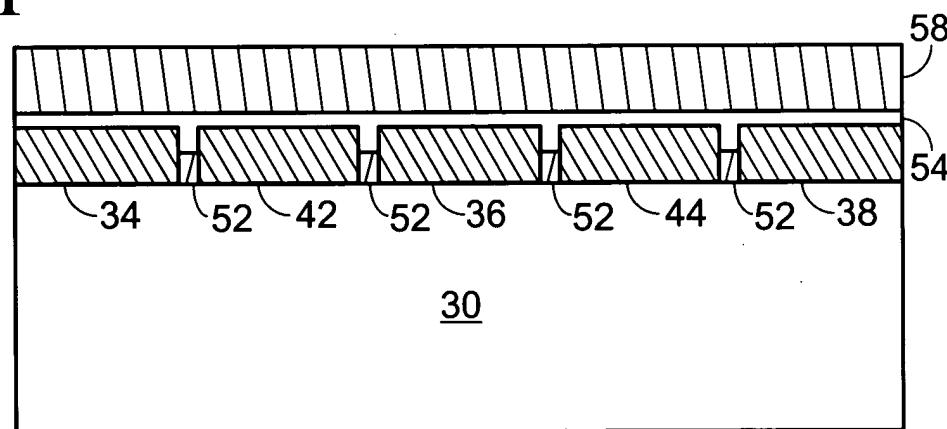




Fig. 12

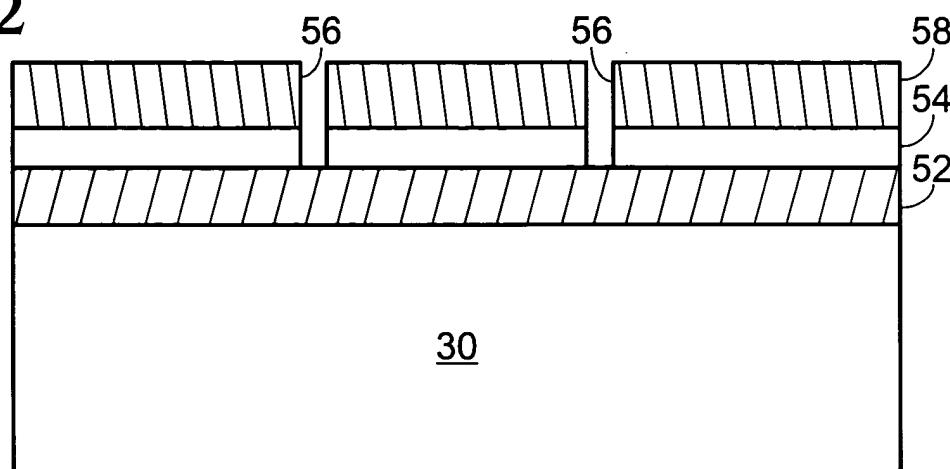


Fig. 13

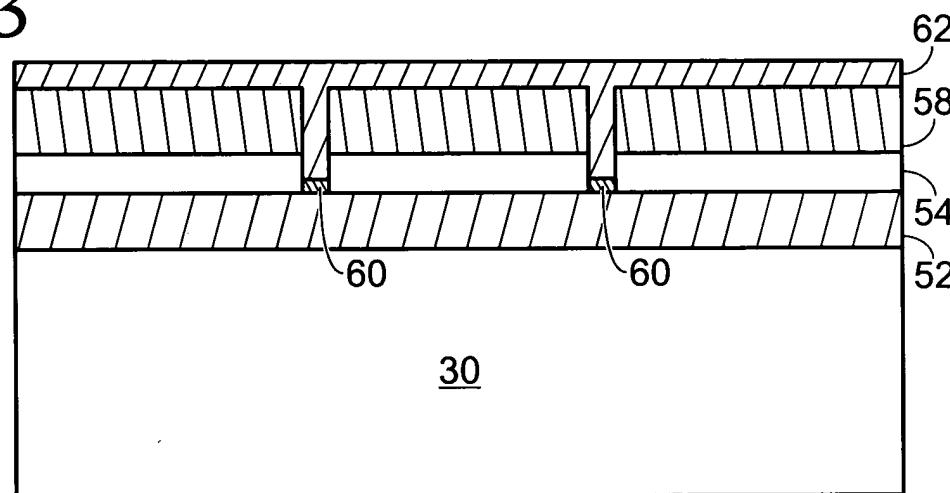


Fig. 14

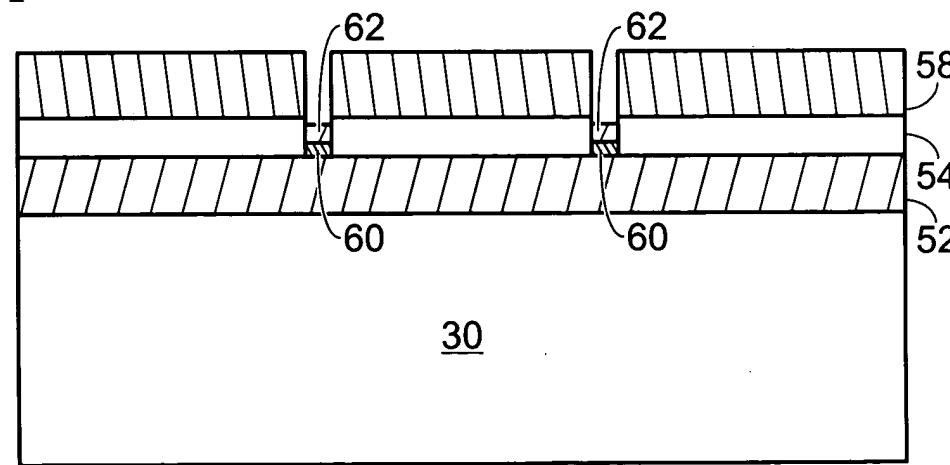




Fig. 15

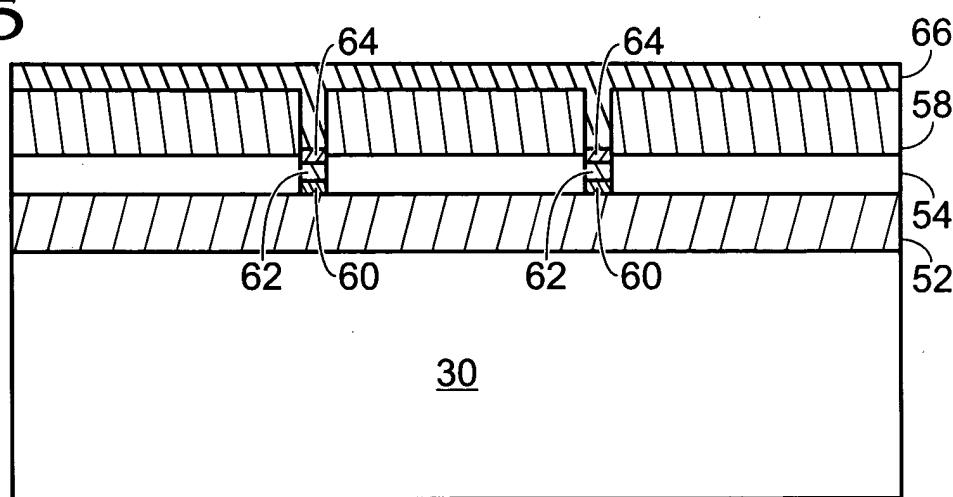


Fig. 16

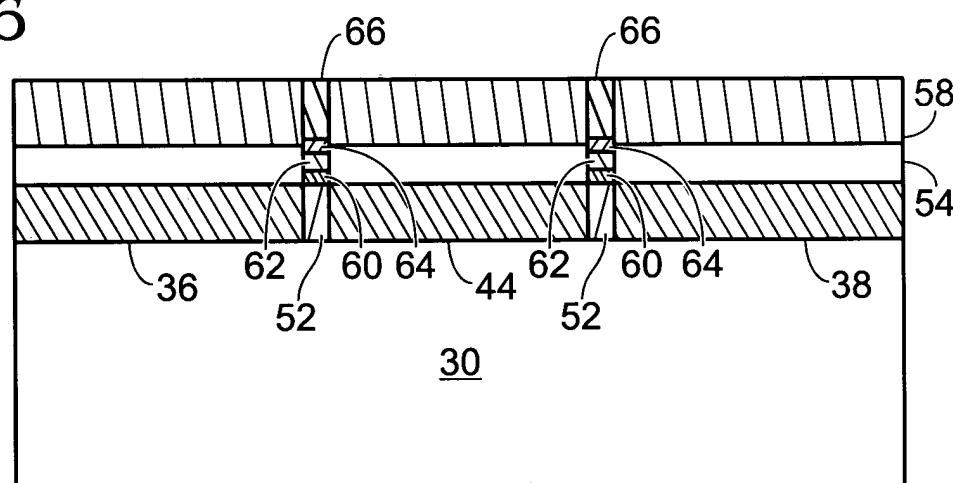


Fig. 17

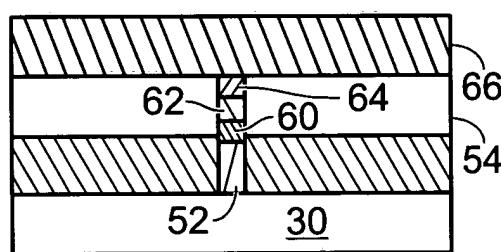


Fig. 18

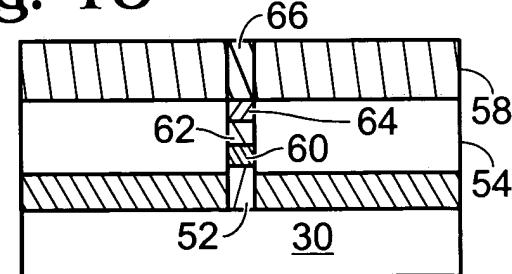




Fig. 19

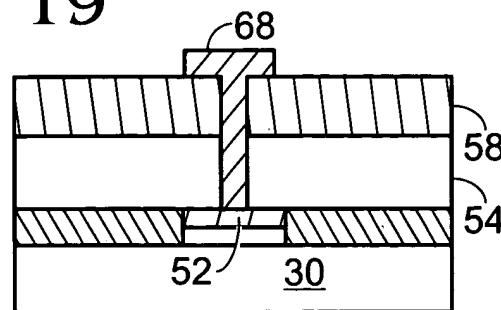


Fig. 20

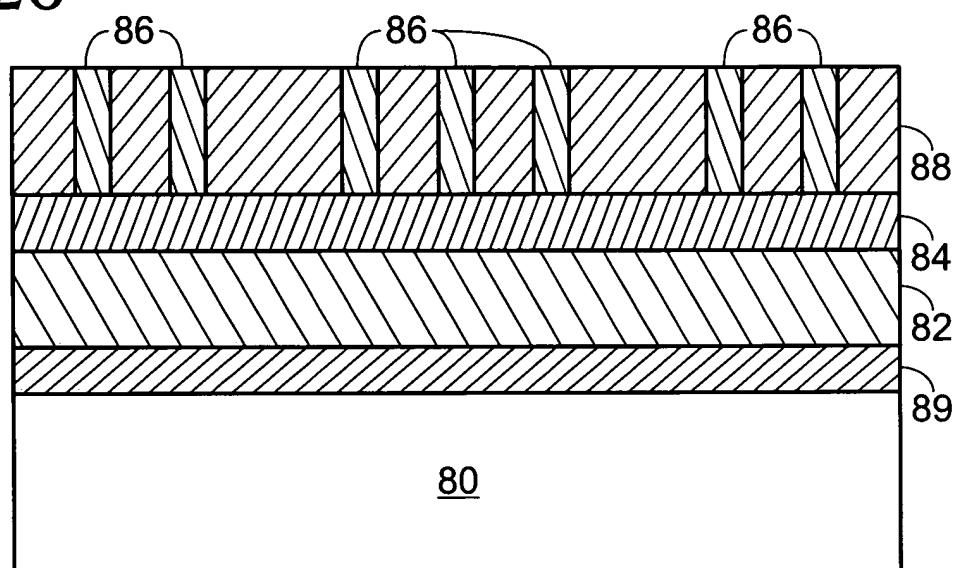
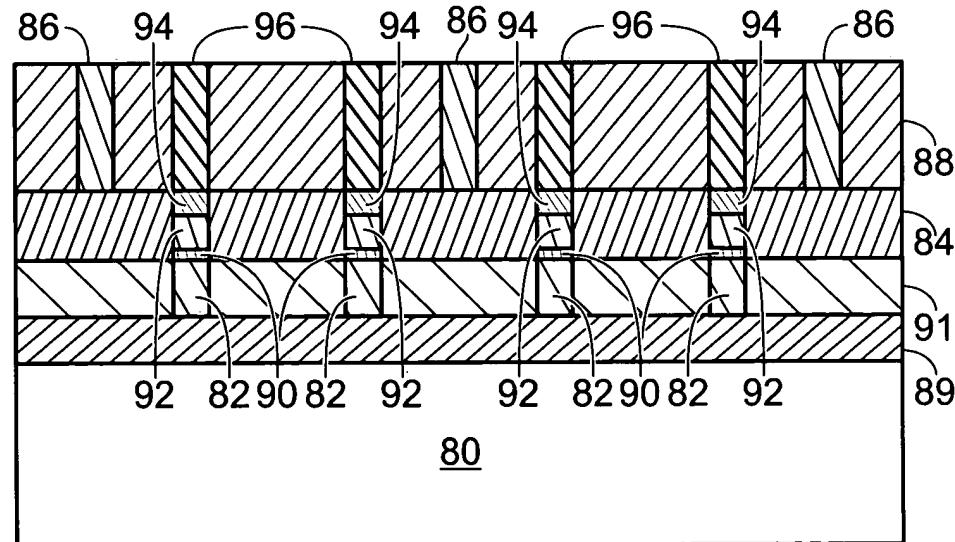


Fig. 21





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Fig. 22

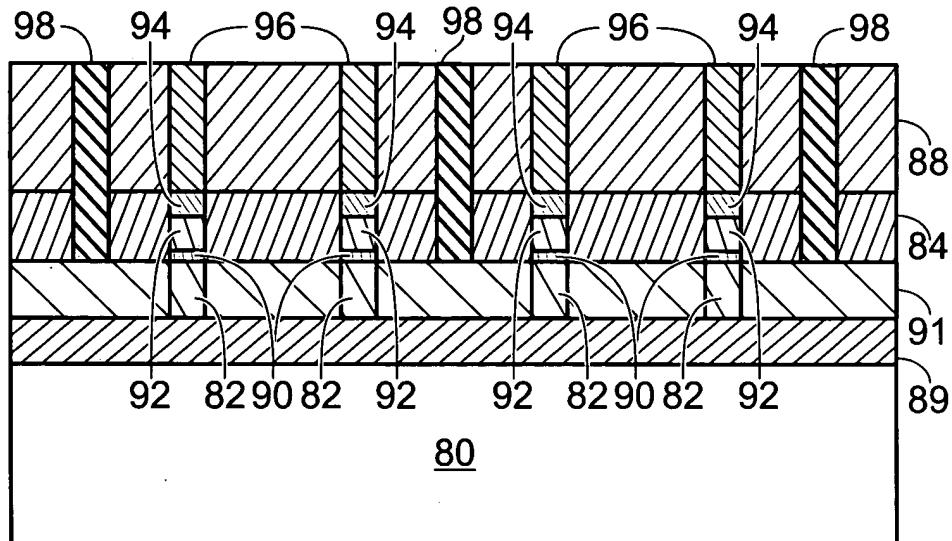
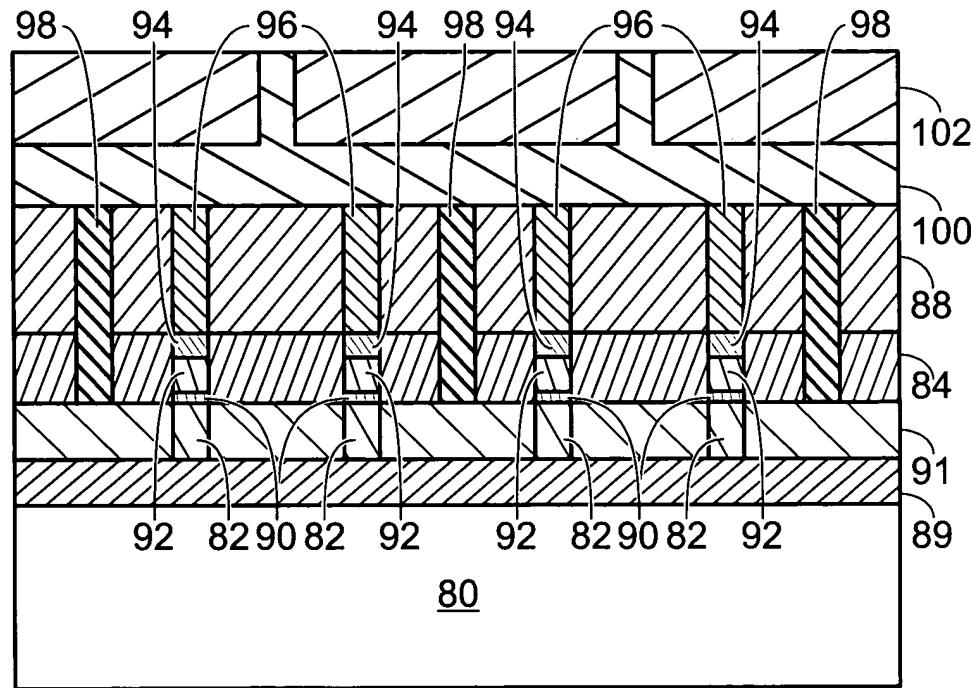


Fig. 23



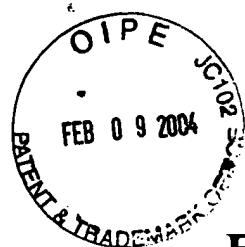


Fig. 24

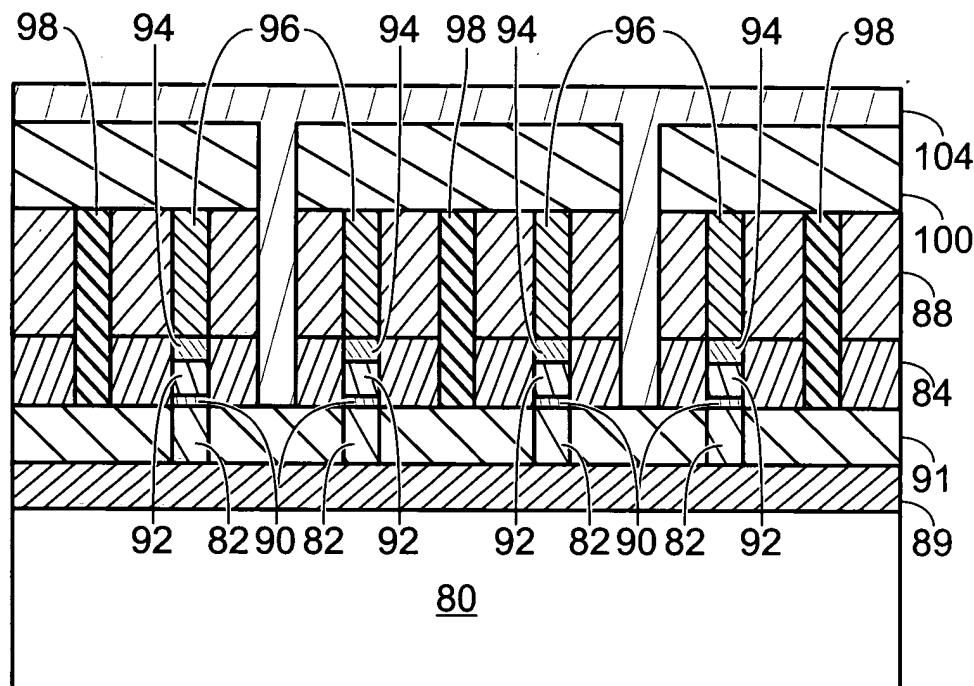


Fig. 25

